- 1 1. A method comprising:
- 2 forming a photoresist using a photoacid generator
- 3 having a first ring including iodine or sulfur and an
- 4 aromatic ring.
- 1 2. The method of claim 1 including forming said
- 2 first ring as a sigma-bonded ring.
- 1 3. The method of claim 1 including forming an
- 2 aromatic ring as a phenyl group.
- 1 4. The method of claim 1 including forming a napthyl
- 2 ring structure.
- 1 5. The method of claim 1 including bonding said
- 2 first ring directly to said aromatic ring to form a napthyl
- 3 ring.
- 1 6. A photoresist comprising:
- a photoacid generator including a first ring with
- 3 iodine or sulfur, and an aromatic ring bonded to said first
- 4 ring.
- 1 7. The photoresist of claim 6 including two aromatic
- 2 rings coupled to said first ring.

- 1 8. The photoresist of claim 6 wherein said first
- 2 ring is sigma-bonded.
- 1 9. The photoresist of claim 6 wherein said aromatic
- 2 ring is a phenyl group.
- 1 10. The photoresist of claim 6 wherein said first
- 2 ring is directly bonded to said aromatic ring to form a
- 3 napthyl ring structure.
- 1 11. A photoresist comprising:
- a photoacid generator including a first ring and
- 3 an aromatic ring directly bonded to said first ring; and
- 4 said first ring including two atoms selected from
- 5 the group including iodine and sulfur.
- 1 12. The photoresist of claim 11 wherein said first
- 2 ring is sigma-bonded.
- 1 13. The photoresist of claim 11 including two
- 2 aromatic rings bonded to said first ring.
- 1 14. The photoresist of claim 13 wherein said aromatic
- 2 rings are bonded on opposite sides of said first ring.

- 1 15. The photoresist of claim 6 wherein said aromatic
- 2 ring is a phenyl group.
- 1 16. The photoresist of claim 11 wherein said aromatic
- 2 ring has an alkyl, phenyl, or caged alkyl attached to said
- 3 ring.
- 1 17. The photoresist of claim 11 including an anion
- 2 selected from the group of ClO₄, SbF₆, and perfluoroalkyl
- 3 sulfonate.